



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Reissue Application of:)

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Inventor: Kiichi HAMA et al.)

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For: PLASMA PROCESS
APPARATUS)

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Washington, DC 20231

Sir:

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APPENDIX TO AMENDMENT FILED MAY 9, 2002

IN THE CLAIMS:

124. (Twice Amended) The apparatus according to claim [123] 120, wherein
said inactive gas supplied into said auxiliary container portion is a coolant, by which said
planar spiral coil is cooled.

137. (Amended) The apparatus according to claim [123] 120, wherein said
pressure controller controls an output of said exhaust pump according to an amount of
inactive gas supplied by said auxiliary supply.